

CLAIMS

1. A discharge processing method, wherein an insulating processing medium is interpolated between an electrode and a processing subject and discharging energy is supplied between the electrode and the processing subject so that the processing subject is processed by the discharge, wherein a processing is carried out with the electrode being pressed onto the processing subject at a predetermined pressure so as to allow the processing medium to form a thin film while the electrode and the processing subject are being relatively moved.
 2. The discharge processing method according to claim 1, wherein the thin film is formed with a thickness of 0.1 to 1 μm .
 3. The discharge processing method according to claim 1, wherein the relative movement is carried out in a spiral manner.
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4. The discharge processing method according to claim 1, wherein a lubricant is used as the processing medium.
 5. The discharge processing method according to claim 1, wherein grease is used as the processing medium.

6. The discharge processing method according to claim 1, wherein a material formed by allowing a polymeric water absorber to absorb water is used as the processing medium.

5 7. The discharge processing method according to claim 1, wherein silicon powder is mixed into the processing medium.

8. The discharge processing method according to claim 10 1, wherein a green compact, which is formed by compressing and molding metal such as titanium that forms a hard compound such as titanium carbide (TiC) or powder thereof, is used as the electrode, and a processing medium containing carbon is used as the processing medium.

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9. The discharge processing method according to claim 1, wherein a green compact, formed by compressing and molding the same material as that of the processing subject or powder thereof, is used as the electrode.

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10. The discharge processing method according to claim 1, wherein the contact area between the electrode and the processing subject, the pressing pressure, the relative shifting rate and the viscosity of the processing medium 25 are used as parameters, and in that the film thickness of

the processing medium between the electrode and the processing subject is controlled by changing at least one of these parameters.

5 11. The discharge processing method according to claim 1, wherein a conductive wire is used as the electrode.

12. The discharge processing method according to claim 1, wherein the processing is carried out while the electrode 10 is being rotated.

13. A discharge processing device, wherein an insulating processing medium is interpolated between an electrode and a processing subject and discharging energy is supplied 15 between the electrode and the processing subject so that the processing subject is processed by the discharge, characterized by comprising:

a pressing unit which presses an electrode onto a processing subject with a predetermined pressure; and

20 a driving unit which moves the electrode and the processing subject relative to each other,

wherein a processing is carried out while the electrode is pressed onto the processing subject at a predetermined pressure so as to allow a processing medium to form a thin 25 film with the electrode and the processing subject being

relatively moved.

14. The discharge processing device according to claim
13, wherein the thin film is formed with a thickness of 0.1
5 to 1 μm .

15. The discharge processing device according to claim
13, wherein the relative movement is carried out in a spiral
manner.

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16. The discharge processing device according to claim
13, wherein a lubricant is used as the processing medium.

17. The discharge processing device according to claim
15 13, wherein grease is used as the processing medium.

18. The discharge processing device according to claim
13, wherein a material formed by allowing a polymeric water
absorber to absorb water is used as the processing medium.

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19. The discharge processing device according to claim
13, wherein silicon powder is mixed into the processing
medium.

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20. The discharge processing device according to claim
13, wherein a green compact, which is formed by compressing
and molding metal such as titanium that forms a hard compound
such as titanium carbide (TiC) or powder thereof, is used
5 as the electrode, and a processing medium containing carbon
is used as the processing medium.

21. The discharge processing device according to claim
13, wherein a green compact, formed by compressing and
10 molding the same material as that of the processing subject
or powder thereof, is used as the electrode.

22. The discharge processing device according to claim
13, further comprising a control unit which controls the
15 contact area between the electrode and the processing subject,
the pressing pressure, the relative shifting rate and the
viscosity of the processing medium as parameters, and gives
an instruction for changing at least one of the pressing
pressure and the relative shifting rate.

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23. The discharge processing device according to claim
13, wherein a conductive wire is used as the electrode.

24. The discharge processing device according to claim 13, further comprising a rotation unit which rotates the electrode.

5 25. The discharge processing device according to claim 13, further comprising:

a state memory unit which controls state changes between setting and resetting states;

10 a discharge energy charging unit containing a current regulating element that is driven by the setting state of the state memory unit made by a discharge instruction pulse;

a discharge energy accumulation unit that is charged by the discharge energy charging unit;

15 a discharge current control unit containing a discharge current regulating element placed between the discharge energy accumulation unit and the electrode; and

an excessive energy discharging unit which is connected to the discharge energy accumulation unit and contains a current regulating element that is driven by the 20 resetting state of the state memory unit,

wherein the state memory unit is reset with a predetermined time delay after a generation of a discharge between the electrode and the processing subject so that the excessive energy discharging unit is driven.

26. The discharge processing device according to claim
13, wherein the power supply device includes,

a state memory unit which is inverted in its ON-OFF
states by a discharge instruction pulse;

5 an AC rectangular wave power supply unit which is driven
by the state memory unit, and includes a switching element
that alternately connects the positive and negative
electrodes of a dc power supply;

10 a discharge current control unit which is placed
between the AC rectangular wave power supply unit and the
electrode, and includes a capacitor and a current regulating
element; and

15 a discharge energy control unit which is connected
to the discharge current control unit, and is constituted
by the capacitor and the current regulating element,

wherein a change in charge at the time when the ac
rectangular power supply unit is switched between the
positive and negative states in its output is allowed to
form discharging energy.